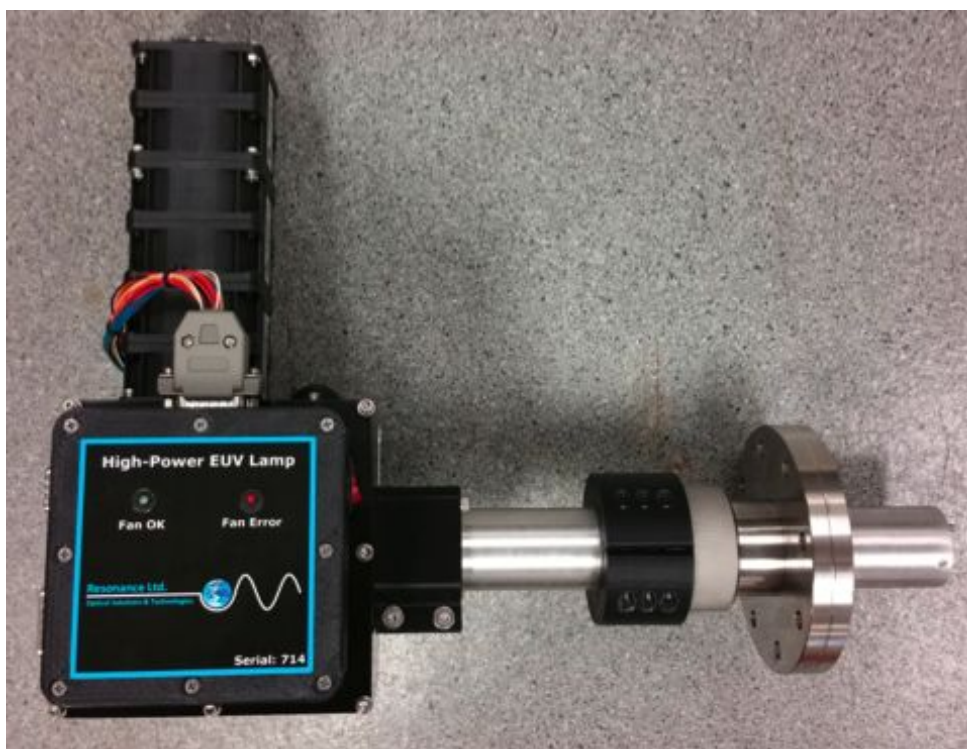
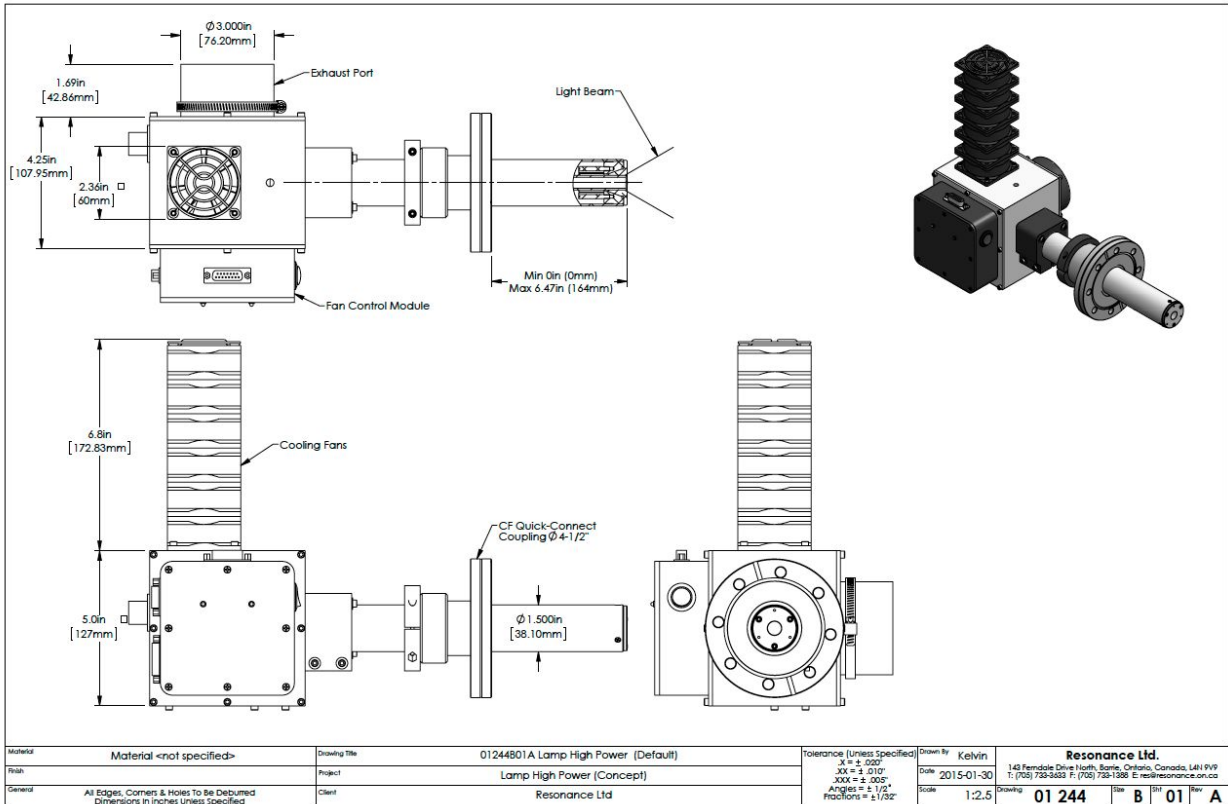


# High Power Lamps



**High-Power VUV Light Sources: Model Numbers KrCM-LHP, XeCM-LHP**

This RF powered lamp system is a reliable and maintenance-free high intensity source of deep VUV emissions between 116 and 200 nm. This source mounts to a 4.5-inch CF flange for easy connection to a high-vacuum system. The lamp is re-entrant to allow optimum positioning. VUV fluxes greater than 100 milliwatts/sterad are delivered through the MgF2 window for vacuum applications such as photoionization TOF mass spectroscopy. Lamp bulbs are interchangeable for easy replacement. The temperature-controlled high-speed fan eliminates the need for water cooling. Normally this source will operate with either a Krypton or Xenon Bulb. These bulbs are interchangeable and other bulbs and or fill pressures are available on a custom basis.



<b>Electrical /Optical Specifications/General:</b>				
<b>Specification</b>	<b>Minimum</b>	<b>Typical</b>	<b>Maximum</b>	<b>Units</b>
Available bulbs		Krypton or Xenon		-
Peak wavelengths Krypton	-	116.5, 123.6, 145	-	NM
Peak Wavelengths Xenon		147, 172		NM
VUV Intensity Krypton		1x10 <sup>17</sup>		Ph/sec./st.
VUV Intensity Xenon		2x10 <sup>17</sup>		Ph/sec./st.
Full angle output cone	15	16	17	Degrees
Window Material		MgF <sub>2</sub>		-
Clear Aperture		0.9		CM.
Certification	Calibration of Irradiance in Vacuum			
Input Power	5	100	300	Watts
Input voltage	70	115	260	VAC
Input Line Frequency	50	60	65	Hz
Mounting flange	4.5 inch CF is standard, lamp can be sealed to HV system			
Cooling	Forced air cooling with variable speed fan			
System	Complete system includes RF power supply, EMI shielded enclosure, Vacuum flange, operating manual, all cables and NIST Traceable calibration			

Power pattern

